NEW AND/OR INTERESTING IN MICROSCOPY

SEEKING NEW EMPLOYMENT? Due to previous interest, we will in our June issue repeat publishing background/qualification summaries of readers seeking new employment. Summaries, with a 50 word maximum, will be published if received prior to 2 June 1995..

Should you wish to keep your interests on the "quiet side", we will utilize a "box" system where potential employers can contact us and we, in return, will pass on that interest to you.

While we will not charge for this effort, we will request (not require) that participants contribute an article or material suitable for publication in the newsletter. Of any length, the only criteria is that the article/material be of interest to a reasonable number of working microscopists.

➡ According to a recent report, a record 39,754 doctorates were awarded in the U.S. in 1993, 2.3% over the previous high in 1992.

Women received 38% of all Ph.D.s in 1993, up from 37% in 1992, 34% in 1983, and 11% in 1963. Men, with 24,646 in 1993, fell short of their peak number - 27,754 doctorates in 1972.

The share of Ph.D.s earned by non-U.S. citizens has increased steadily over the past 30 years, reaching 32% in 1993 - 6% for permanent residents and 26% for temporary residents. Over half the non-U.S.-citizen recipients come from four Asian nations (China - 2,254, Taiwan - 1,452, South Korea - 1,405, India - 1,134).

➡ The Characterization Facility at the Center of Interfacial Engineering, University of Minnesota, will present a master class on CryoTEM of Colloidal Materials on Thursday and Friday, May 18 and 19, 1995. The course will include lecture and laboratory sessions covering specimen preparation, cryotransfer to the microscope, low-electron dose image and diffraction pattern recording on film and slow-scan CCD and image-processing and analysis of digital CryoTEM images. For further information, contact Beth Trend: (612)624-1365.

NEW PRODUCT NEWS

Scanalytics, the bio-instrumentation and software division of CSPI, recently announced the release of its deconvolution software for high-resolution fluorescence microscopy. Known as Exhaustive Photon Reassignment (or EPR™) the technology makes it possible to visualize and study the inner workings of healthy or diseased cells and tissues. Used by biologists for greatly increasing resolution of images acquired through a fluorescence microscope, the technique allows two-dimensional and three-dimensional visualization and study of intracellular structures and processes. The EPR software is now available for independent use on a Pentium™ processor under the MS-Windows™ operating system. Scanalytics, 40 Linnell Circle, Billerica, MA 01821. (800)325-3110, Fax: (508)663-0150. Circle Reader Inquiry #30.

M.E. Taylor Engr., Inc. is pleased to introduce "Lift-N-Press" (L-N-P) transfer adhesive tabs. "L-N-P" is a thin film of a high tac adhesive used to hold samples in place on SEM mounts, secure photos, collect particulates, obtain gun shot residue samples, etc.

L-N-P tabs are about 12 mm x 12 mm. They are curved on one end to fit SEM mounts. The background looks relatively smooth, making particulates easy to observe. This new product has many advantages over other products.

Lift-N-Press will be available through most suppliers of EM related products and some photographic centers. Call for a brochure or Free Sample. M.E. Taylor Engr., Brookeville, MD. Phone: (301)774-6246. Fax: (301)774-6711. Circle Reader Inquiry #31.

Digital Instruments announces the new Signal Access Module™ (SAM™). This module will allow researchers to access every signal going into and out of the NanoScope III controller for custom-designed experiments. Fifty BNC connectors and twenty-five hardware switches give you access to every signal between the NanoScope III or IIIa controller and your SPM. Each signal can be monitored, modified, or generated externally and then injected into your system. Each analog-to-digital convertor (ADC) input can be software configured so that the data is automatically displayed and stored with the proper units, polarity and scaling. Digital Instruments, 520 East Montecito St., Santa Barbara, CA 93103. (805)899-3380, Fax: (805)899-3392. Circle Reader Inquiry #32.

Leica Inc. has recently launched the LEICA Stereoscan S400σ Series of scanning electron microscopes, a powerful integrated analytical package combining a LEICA Stereoscan S400 SEM with a Kevex Sigma Microanalyser. Ease of use is assured by the Microsoft Windows-based graphical environment of both instruments and the multi-tasking acquisition system of the VME-based Sigma, offering an analytical station with simplicity, flexibility and complete automation.

Windows-level integration of the LEICA Stereoscan and Sigma operating systems makes it possible for experimental data to be exchanged between the two systems throughout the analysis. These data include operating conditions, system status and image information. All operations are achieved with the convenience of single mouse and keyboard operation. A range of detectors is available, including the premium grade Mark VI Si(Li) and the patented SuperDry liquid nitrogen-free series.

This powerful system is both simple to operate and flexible enough to grow further with optional hardware and software packages. The design of the LEICA Stereoscan and Sigma software operating in the Windows environment makes it easier than ever to acquire images, maps and assorted data. These may be archived or pasted into report generation software, either during the actual analysis or off-line. Furthermore, the inherent networking capabilities of the system enable other workstations to be easily connected, permitting remote access to data produced during the analysis.

For more information, contact Leica Inc., 111 Deer Lake Road, Deerfield, IL 60015, (800)248-0123, Fax: (708)405-0147. Circle Reader Inquiry #34.

FEI Company's Components Group announces a new 2-lens Electron Column that offers both small spot size for high-resolution imaging (less than 20 nanometers) and high beam currents for surface analysis techniques where signal-to-noise ratios and fast acquisition times are critical. The column operates at beam voltages of 0.5 kV to 25.0 kV with beam currents from less than 50 picoamps to more than 200 nanoamps. It is designed for incorporation in scanning and transmission electron microscopy (SEM and TEM), Auger electron spectroscopy (AES), electron spectroscopy for chemical analysis (ESCA), micro-RHEED, and low-energy electron diffraction (LEED) systems. FEI Company, 7451 NE Evergreen Parkway, Hillsboro, OR 97124. (503)640-7500, Fax: (503)640-7509. Circle Reader Inquiry #35.